TWO-AXIS ACCELERATION SENSOR FOR MEDICAL APPLICATIONS

The sensing device is a two axis

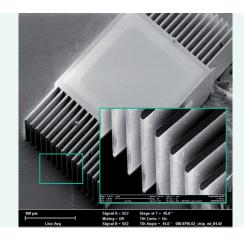
micromechanical acceleration sensor with

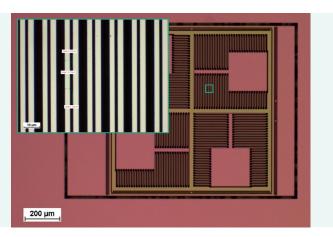
capacitive detection. The MEMS is fabri-

cated using the BDRIE technology. BDRIE

stands for Bonding and Deep Reactive

Ion Etching. The MEMS core die has a





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dimension of $(1 \times 1) \text{ mm}^2$. The complete die size is $(1.2 \times 1.5) \text{ mm}^2$. Each axis has two differential capacitances to extract the acceleration data. The table below summarizes the target specification for the accelerometer.

Description	Sign	Value	Unit
Measurement range	±	5	g
Natural frequency	~	2	kHz
Number of axis		2	
Number of electrodes per axis		2	
Base capacitance of one electrode	~	2.5	pF
Capacitive sensitivity of one electrode	>	50	fF/g
Spring stiffness (x direction)		3.6	N/m
Spring stiffness (y direction)		5.8	N/m
Typical polarization voltage	<	1.3	Volt
Dimension L x W		1.2 x 1.5	mm
Thickness		645	μm
Mass	~	3	mg